

10/594153

SAK-5524

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Masanobu KUSUNOKI, et al

Serial No.: not yet assigned

Filed: September 25, 2006

For: PROCESS FOR FORMING THIN FILM AND SYSTEM FOR
FORMING THIN FILM

Group: not yet assigned

Examiner: not yet assigned

INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR §1.97 & 1.98**MS Amendment**Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

September 25, 2006

Sir:

In the matter of the above-identified application, applicants are submitting herewith a copy of a communication from a foreign patent office in a counterpart foreign application and copies of the documents listed in the attached form equivalent to Form PTO-1449 for the Examiner's consideration.

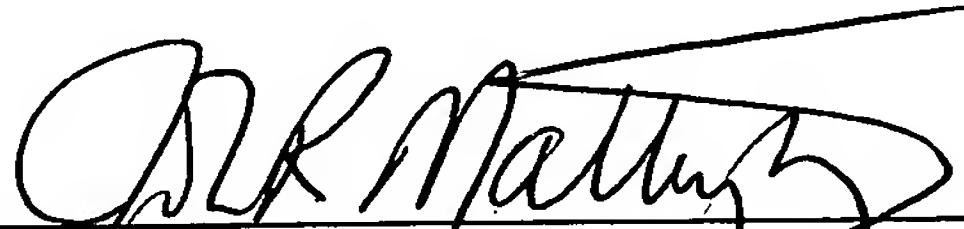
This information disclosure statement is being submitted with the new application.

Although the documents listed on the attached form equivalent to Form PTO-1449 are not in the English language, the requirement of 37 CFR § 1.98(a)(3) for a concise explanation of the relevance is satisfied by the attached English language abstract or partial English translation.

It is respectfully requested that this information disclosure statement be considered by the Examiner.

Please charge any shortage in the fees due in connection with the filing of this paper, including extension of time fees, to the deposit account of MATTINGLY, STANGER, MALUR & BRUNDIDGE, P.C., Deposit Account No. 50-1417 (SAK-5524) please credit any excess fees to such deposit account.

Respectfully submitted,



John R. Mattingly
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MATTINGLY, STANGER, MALUR & BRUNDIDGE, P.C.

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Sheet 1 of 1

Form PTO-1449 INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DKT. NO. SAK-5524	SERIAL NO. NOT YET ASSIGNED
	APPLICANT Masanobu KUSUNOKI, et al		
	FILING DATE September 25, 2006	GROUP Not yet assigned	

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date
AA	6,280,580	08/01	Suh et al.			
AB						
AC						
AD						
AE						
AF						
AG						
AH						
AI						
AJ						
AK						
AL						

FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Subclass	Abstract	
						Yes	No
AM	2000-045072	2/00	JP			X	
AN	8-078338	3/96	JP			X	
AO	60-026661	2/85	JP			X	
AP	7-75689	8/95	JP				X
AQ							
AR							
AS							
AT							

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

AU	"In situ grown YBa ₂ Cu ₃ O _{7-d} thin films from single-target magnetron sputtering" by C.B. EOm, et al. Appl. Phys. Lett. 55 (6), 7 August 1989. pgs. 595-597.	
AV		
AW		
AX		
AY		
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Examiner		Date Considered